

METHOD OF FORMING SILICON-CONTAINING INSULATION
FILM.....

Yasuyoshi Hyodo, et al.

Appl. No.: Unknown Atty Docket: ASMJP.137AUS

Fig. 1

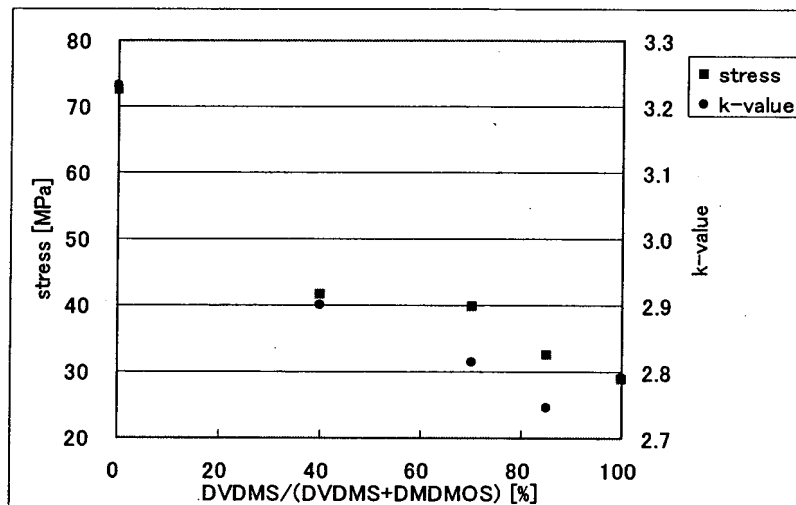


Fig. 2

